Korean International Semiconductor Conference & Exhibition
on Manufacturing Technology 2025

KISM 2025 BUSAN

Re:Innovation of Semiconductor Manufacturing for AI Ecosystem

[ThF2] Carbon Neutrality in Semiconductor Industry II

Session Date	November 13 (Thu.), 2025
Session Time	10:50-12:25
Session Room	Room F (Panorama Room, 16F)
Session Chair	Prof. Hu Young Jeong (UNIST, Korea)

[ThF2-1] [Invited] **10:50-11:15**

Toward Sustainability: Green CVD Approaches for Decarbonizing Semiconductor Fabs

Chulhwan Choi, Mingyo Byeon, Jingyu Park, Byeongsun Yoo, Dongjoon Myung, and Changsoo Lee (Samsung Electronics Co., Ltd., Korea)

[ThF2-2] [Invited] **11:15-11:40**

Improvement of PFC Gas Treatment Technology for Etching Using Catalysts and Its Additional Effects

Yongjin Kim, Sangyoon Kim, and Jongpil Yoon (ECO ENERGEN Co., Ltd., Korea)

[ThF2-3] [Invited] **11:40-12:05**

Case Study on the Demonstration of a White Plume Reduction Device (K-Industry)

Sang Woo Lee, Hyeong Kee Lee, and Seung Han Kwon (NURI PLAN Co., Ltd., Korea)

[ThF2-4] **12:05-12:25**

Low Temperature Etching of SiO_2 and Si_3N_4 Using Low Global Warming C_3F_6, C_3HF_5, and $C_3H_2F_4$

Sumin Park, Daeun Hong, Eunsu Lee, Minsung Jeon, and Heeyeop Chae (Sungkyunkwan Univ., Korea)